

SMASHI & MeLA ECR Ion Sources at NFRI:

One[†] for Highly-charged Ions and the Other[‡] for High Current Metal Ions

The 22nd International Workshop on ECRIS

H. J. YOU, S. O. Jang, W. I. Choo

31, August, 2016

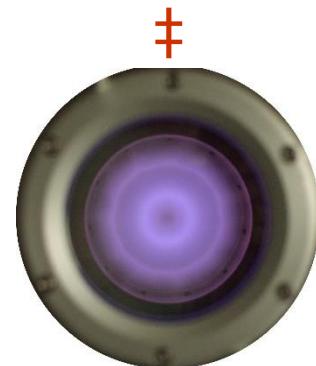
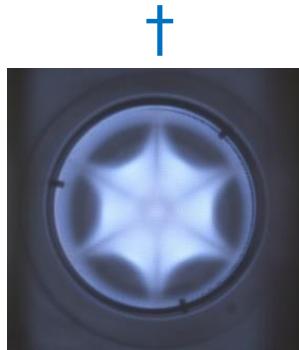
National **F**usion **R**esearch **I**nstitute

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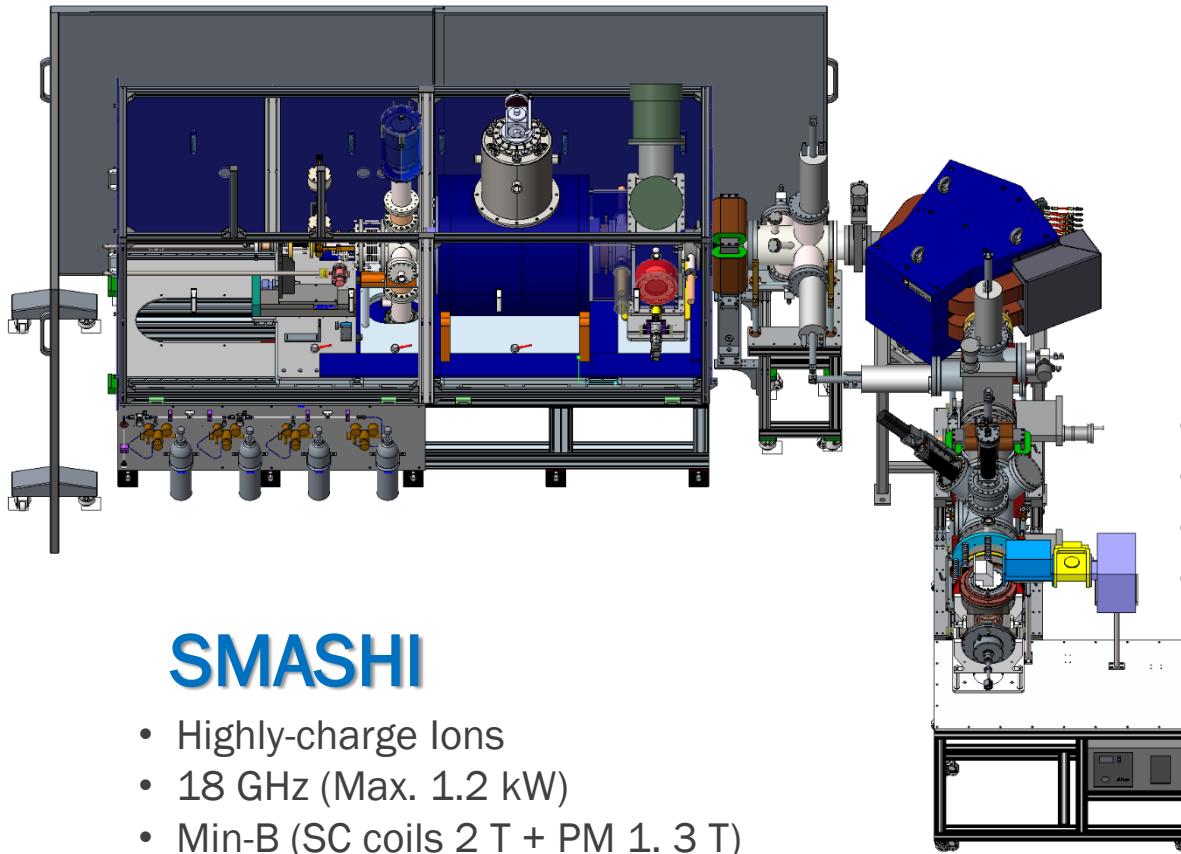
- 1) [†]SMASHI for Medium Current Highly-charged Ions
- 2) [‡]MeLA for High Current Singly-charged Gas/Metal Ions

[†]SMASHI=Superconducting Multi-Application Ion Source for Highly-charged Ions

[‡]MeLA=Magnet-embedded Lisitano Antenna



Layout of NFRI ECR Ion Source Facility



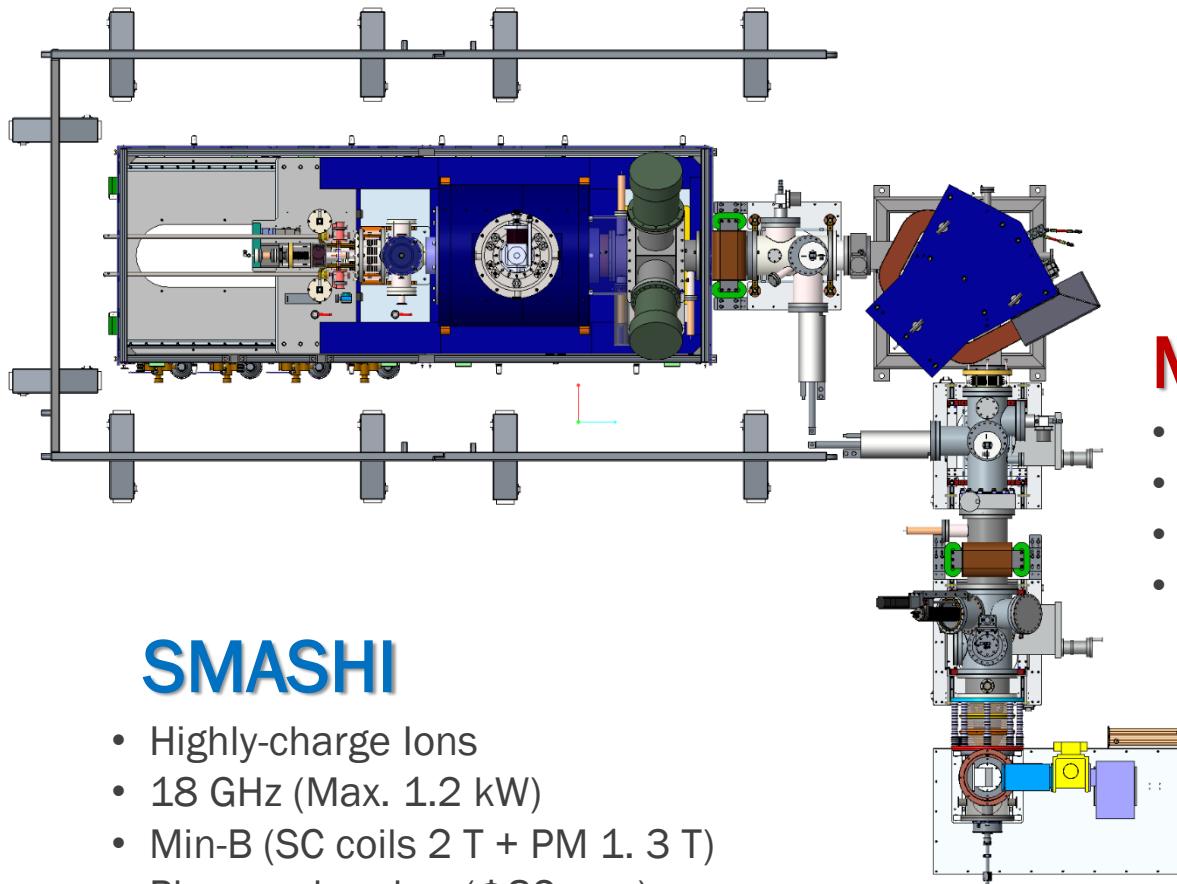
SMASHI

- Highly-charge ions
- 18 GHz (Max. 1.2 kW)
- Min-B (SC coils 2 T + PM 1. 3 T)
- Plasma chamber ($\Phi 82$ mm)

MeLA

- High current metal ions
- 2.45 GHz (Max. 3 kW)
- PM (~ 0.2 T)
- MeLA size ($\Phi 120$ mm)

Layout of NFRI ECR Ion Source Facility



SMASHI

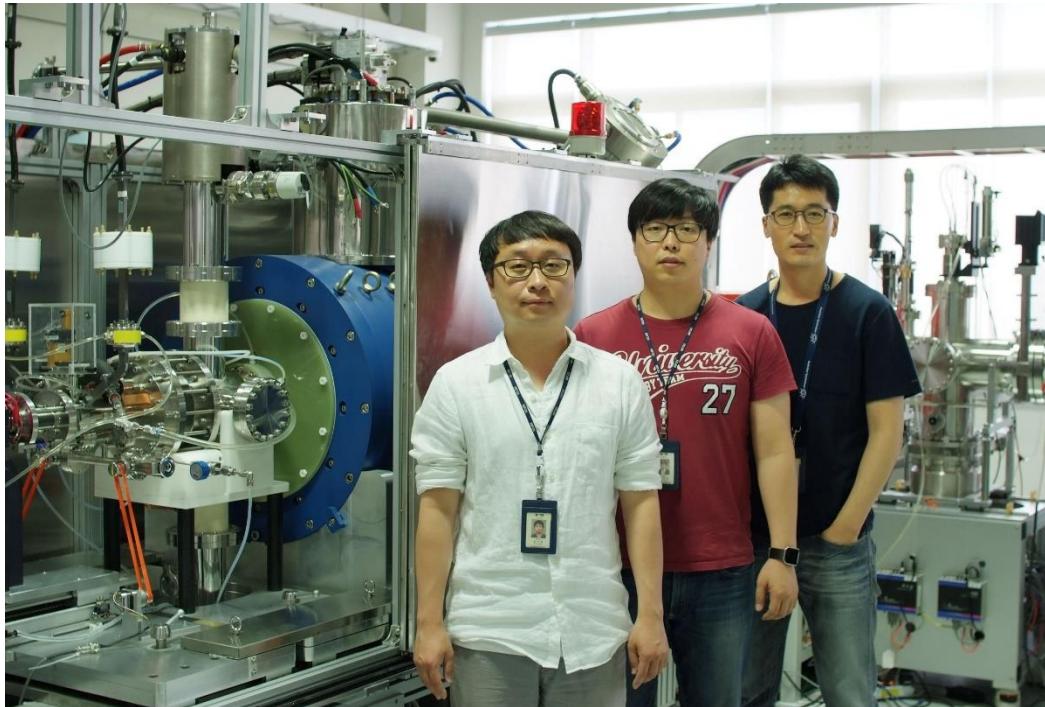
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Microwave Plasma/Ion Source TEAM

» We are three (small team), but still young

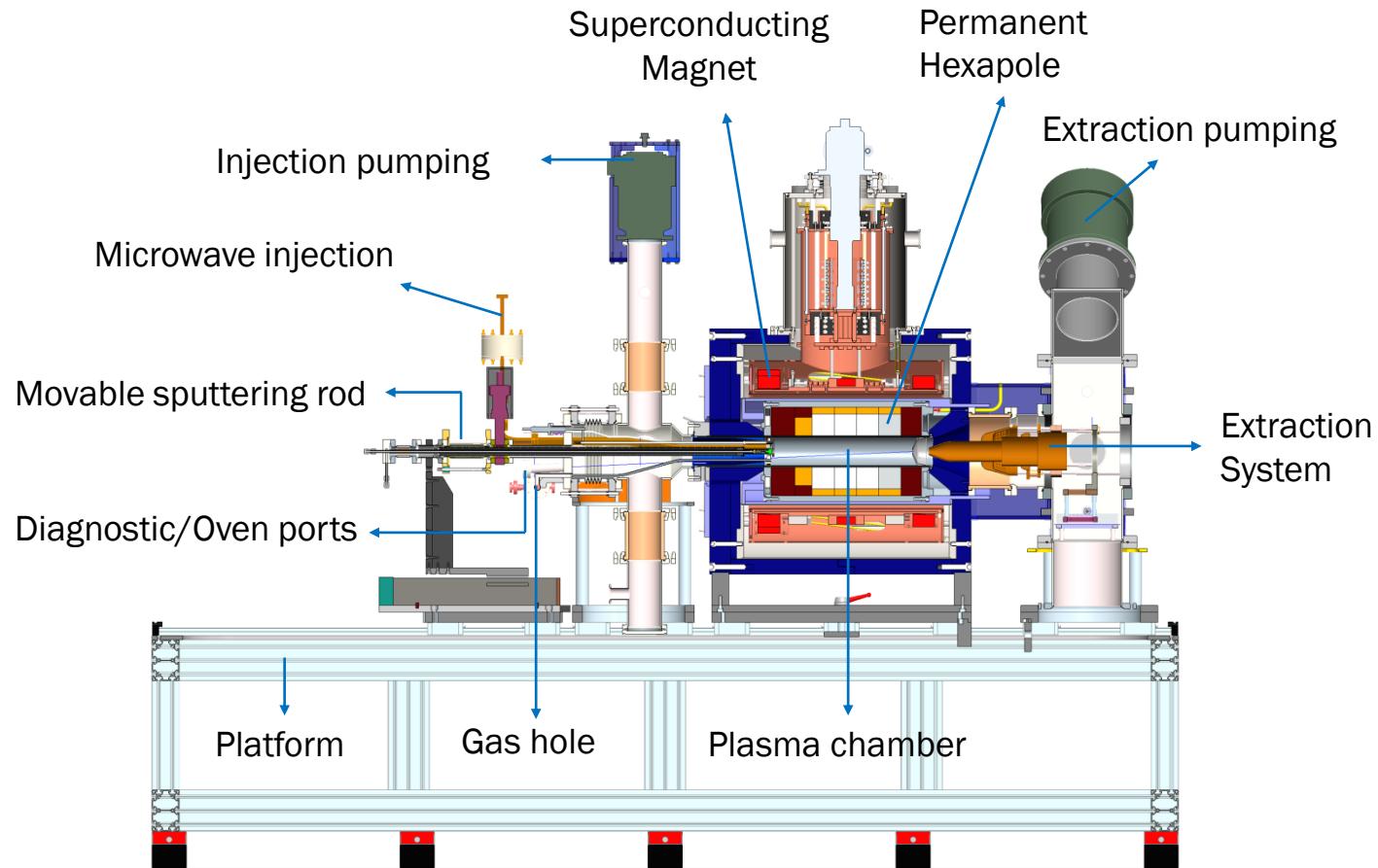


SMASHI



SMASHI

» SMASHI (Superconducting Multi-Application Source of Highly-charged Ions)



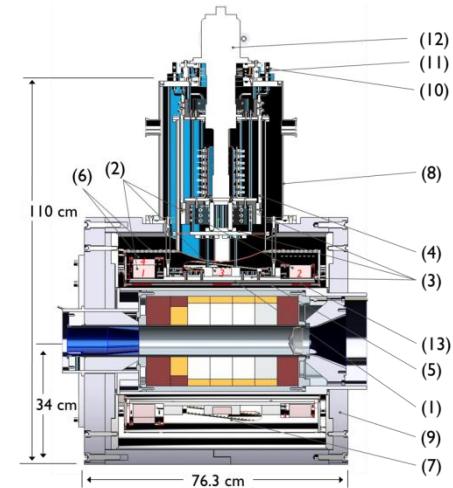
Design Features of SMASHI

Design Features of SMASHI

- » **2.1 T ($B_{\text{inj,max}}$), 1.5 T ($B_{\text{ext,max}}$), 0.4-0.6 T (B_{min})**
 - “Liquid He-free” high field magnet and its flexible tuning
 - Very low power consumption (200 → 15 kW)
- » **1.28 T** of high radial field (permanent magnet hexapole)
- » Two frequency heating (**18, $18 \pm \Delta$ GHz**)
 - 2 set of TWT (Max. power=650 W) can give 1250 W
- » Capability to generate at the same time diverse ion elements from gas to metal
- » High power-capable **Al plasma chamber** ($\varnothing 82 \times 460$ mm=2.2 liter)
- » **Movable extraction-einzel lens system** (15-30 kV) for low beam emittances
- » **Two diagnostic ports** for diagnosing the extraction region of plasma

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Main parameters of magnetic field

f (GHz)	18, $18 \pm \Delta$ (Two frequency)	
$B_{inj, max}$ (T)	2.1	$B_{inj}/B_{ecr} = 3.4 - 4.4$
$B_{ext, max}$ (T)	1.5	$B_{ext}/B_{rad} = 1.2$
B_{ecr} (T)	0.65	
B_{rad} (T)	1.28	$B_{rad}/B_{ecr} \sim 2.0$
B_{last} (T)	1.3	$B_{last}/B_{ecr} = 2.0$
B_{min} (T)	0.4-0.55	$B_{min}/B_{rad} = 0.3 - 0.4$

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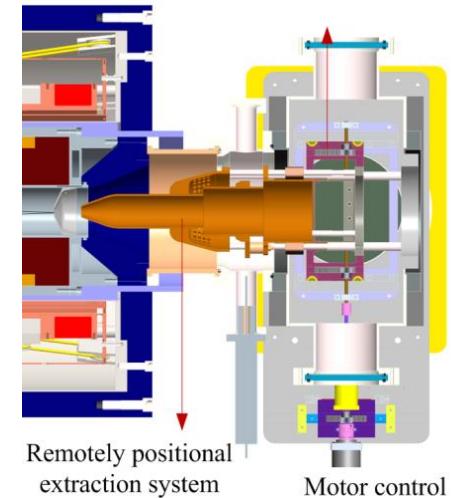


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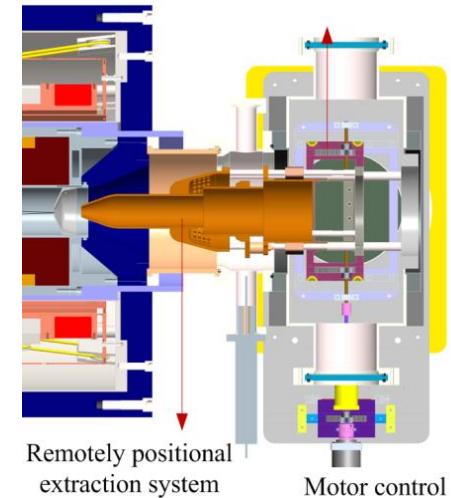
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Purposes of 18 GHz SMASHI at NFRI (1)

» Development of Advanced high-performance ECR ion source

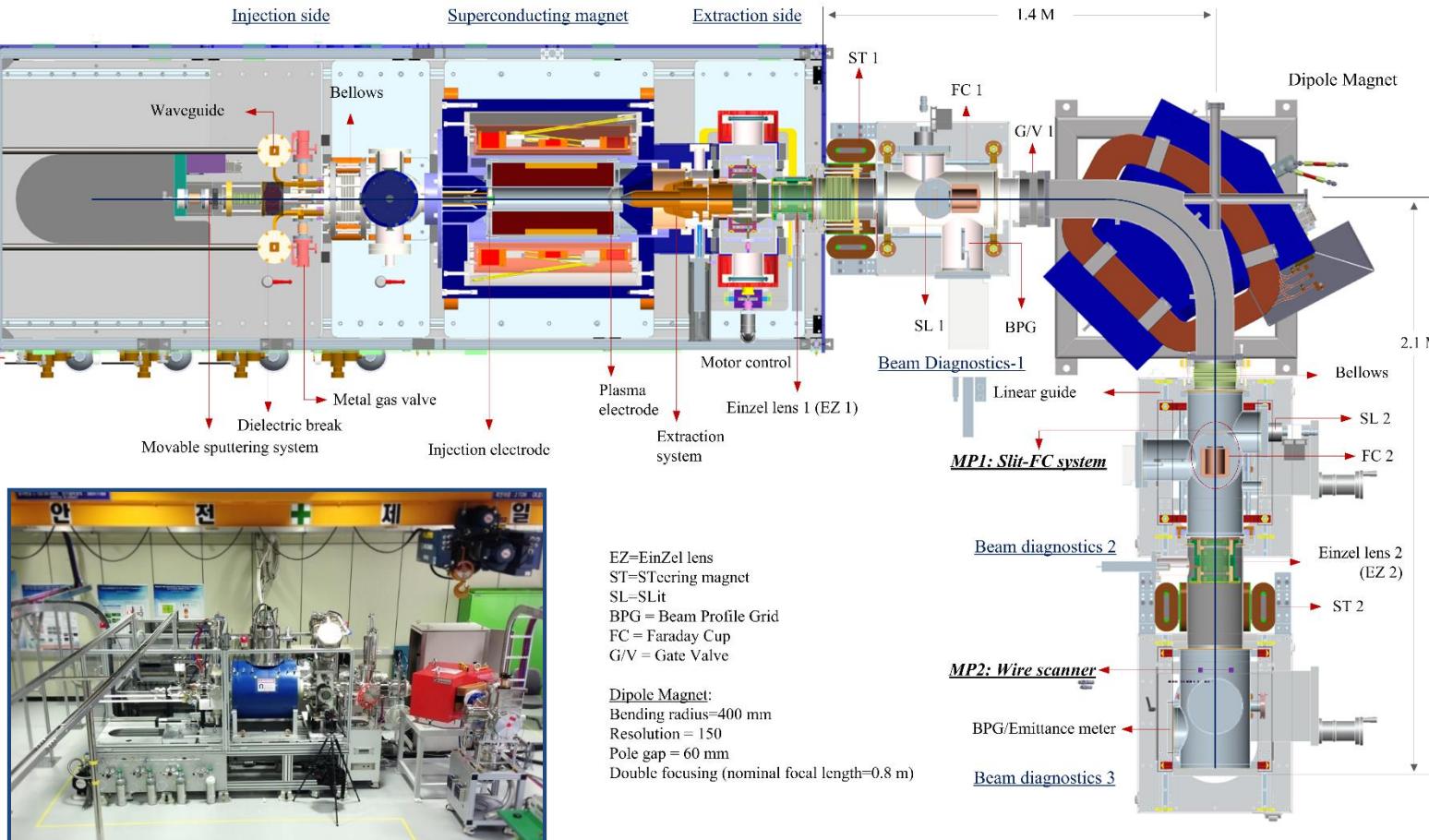
- 1) Studies on ECRIS Plasma
- 2) Development of compact high-performance ECR ion sources
for material(surface) interaction and/or compact heavy ion therapy

» Highly-charged Ion Matter Interaction by using well-defined ion beams

- 1) Investigation of various highly-charged ion-surface interaction
- 2) Ion beam studies & development of new fusion reactor material (C, Be, W...)
- 3) Highly-charged ion induced products (X-rays, highly-excited neutrals)

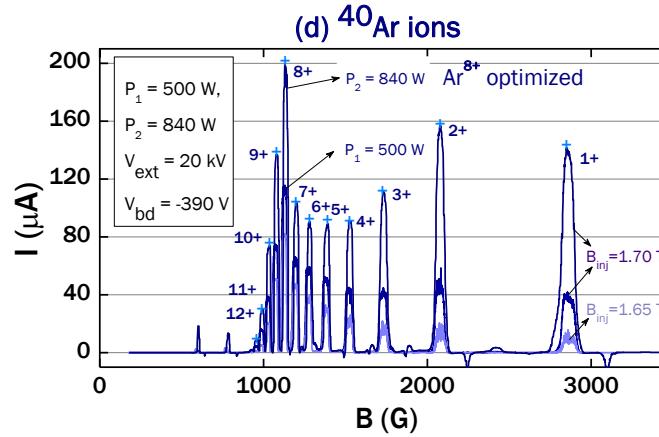
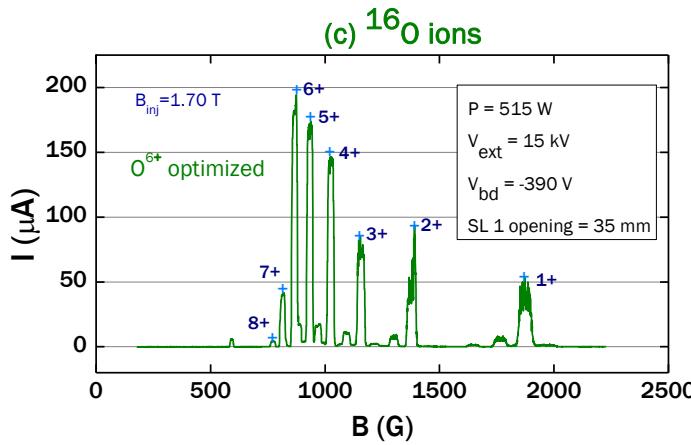
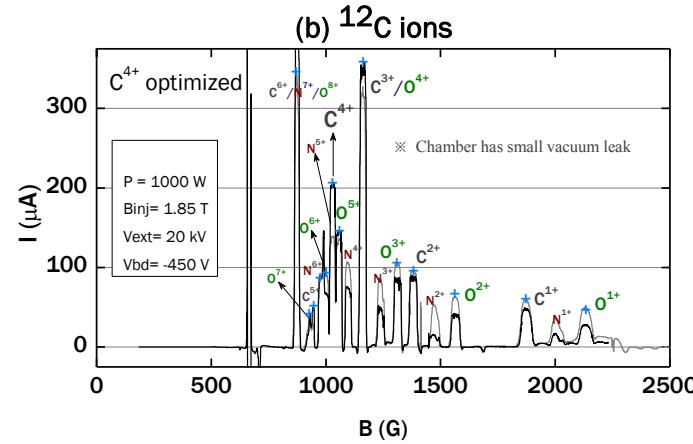
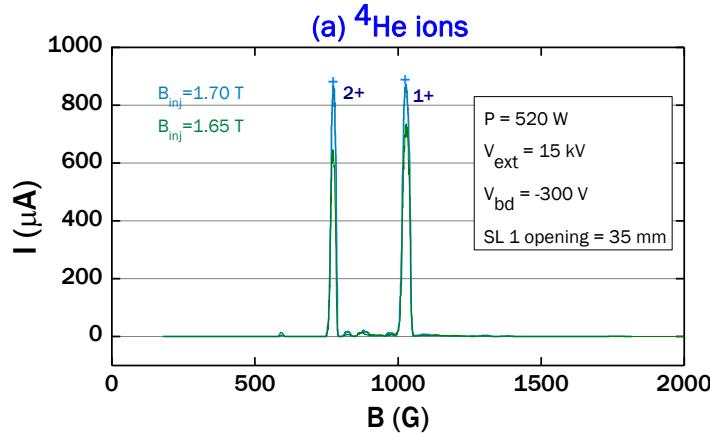
Setup of SMASHI & LEBT

» SMASHI(SC Multi-Application Source of Highly-charged Ions) & its LEBT



Beam charge spectra from SMASHI

» Preliminary beam charge spectra of He/C/O/Ar beams



Initial Beam Results

» Preliminary results of beam charge spectra from SMASHI ($B_{inj}=1.7$ T, Max. power=600/**900 W**)

Charge	⁴He	¹²C		³²O	⁴⁰Ar		¹³²Xe	
	500 W	500 W [†]	1 kW [†]	500 W	500 W	840 W	500 W	900 W
1+	910	200	47					
2+	900*	210	85					
3+		-	-					
4+		100*	206*					
5+		25	49	184				
6+			-	202*				
7+				43	70	105		
8+				4.3	120*	200*		
9+					78	138		
10+					41	75		
11+					18	31		
12+					5	9.4		
13+					1.2	2		
19+							2.7	25
20+							2.5*	23*
21+							2.3	22

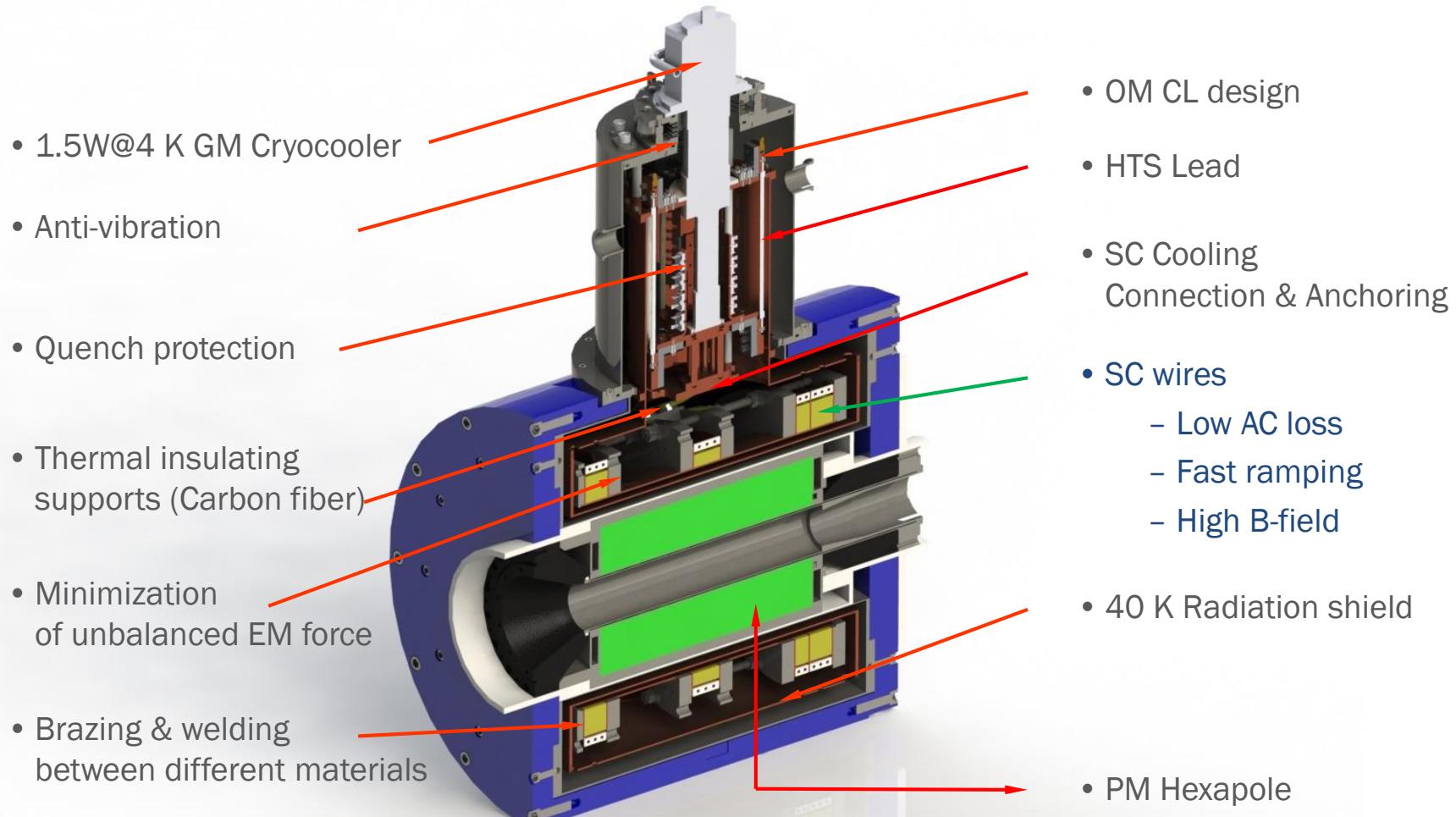
* optimized charge, [†] under small vacuum leak

Operation conditions

- Max.TWT Power = 600 W¹ + 300 W²
Input power was limited to ~900 W due to high X-ray dose rate(>0.5 μ Sv/h) at operator position
- $B_{inj}=1.7$ T (80 %), $B_{ext}=1.3$ T, $B_{min}=0.5$ T
- Extraction voltage ≤ 20 kV, Ø8 mm aperture
- Biased disk voltage = -(200~600) V
- Stainless steel plasma chamber & No gas mixing
- [†] Carbon beam was obtained under small vacuum leak (plasma chamber)

See the poster [WEPP16](#)
for more information

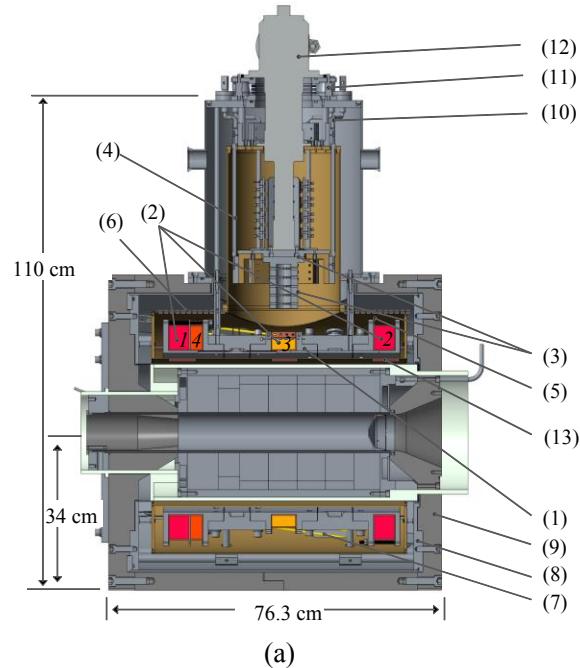
Newly developed Liquid He-free SC Magnet (SM 2)



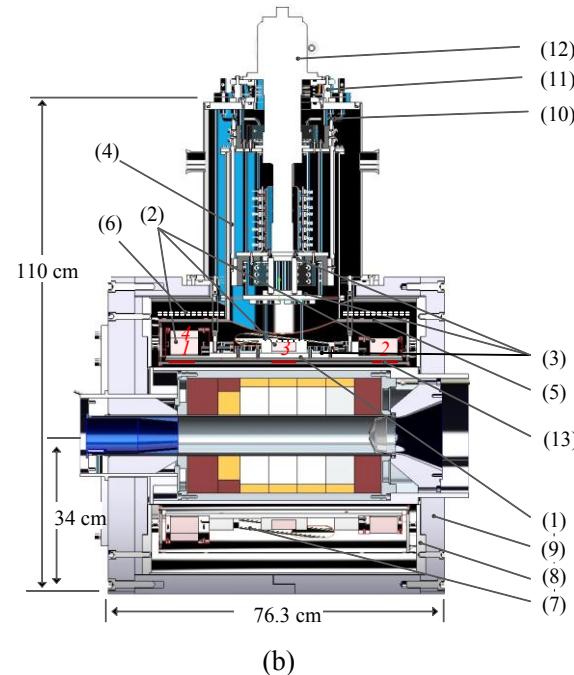
Liquid He-free SC Magnet for high field 18 GHz ECRIS

SM 2 is for Fast Coil Excitation & Tuning

<SM II: NEW>



<SM I: Previous>

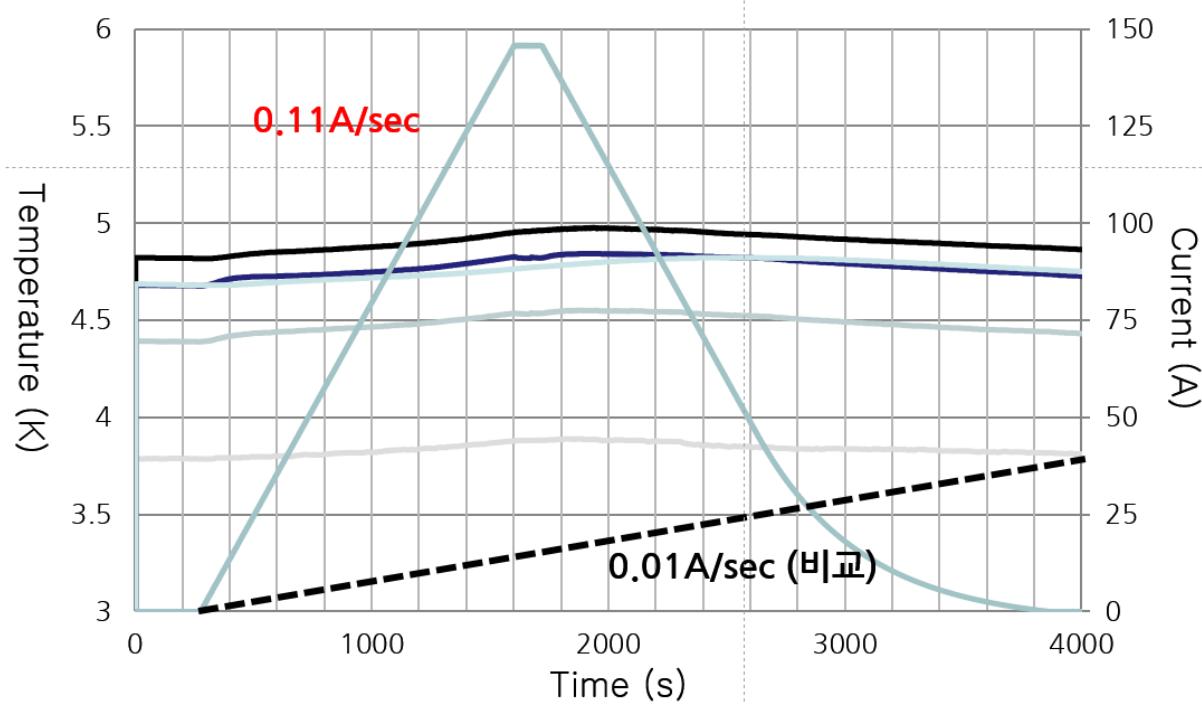


- (a) A newly-upgraded SC magnet capable of fast-ramping & higher magnetic field compared with the previous SC magnet:
- (1) S.S. Bobbin (previous: OFHC bobbin), (2) SC coil, (3) Thermal link, (4) HTS lead, (5) Radiation shield, (6) ML thermal shield, (7) Thermal insulating support, (8) Vacuum chamber, (9) Iron yoke, (10) Current lead, (11) Anti-vibrator, (12) 4 K Cryocooler, (13) Quench protection

How to get fast coil excitation

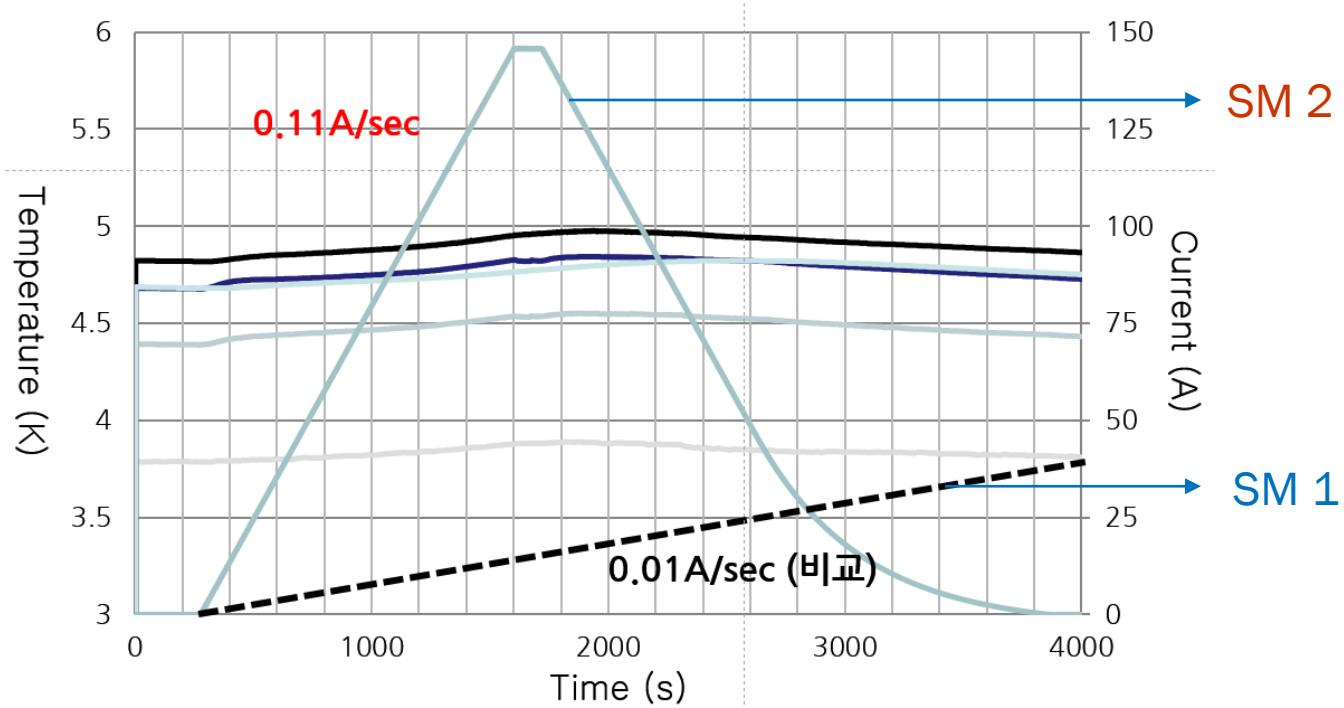
	New (SM II)	Previous (SM I)	Expected Enhancement
Coil bobbin			
Material	¹ SUS304	OFHC Copper	Eddy current loss $\approx 1/3000(220 \text{ J} \rightarrow 0.07 \text{ J})$
Superconducting wire			
Superconductor	NbTi	NbTi	
Wire diameter	$\emptyset 0.8 \text{ (mm)}$	$1.2 \times 0.75 \text{ (mm)}$	Hysteresis loss $\approx 1/10$ $110 \text{ J} \rightarrow 11 \text{ J}$
Filament	<ul style="list-style-type: none">Diameter=10.4 (μm)²Number of filament=1740Twist pitch=18 (mm)	<ul style="list-style-type: none">Diameter$\approx 100 \text{ } \mu\text{m}$Number of filament= 54Twist pitch=42 (mm)	
Matrix	Oxygen Free Copper	Oxygen Free Copper	Eddy current loss $\approx 1/4$ $125 \text{ mJ} \rightarrow 31 \text{ mJ}$
Cu to SC ratio	³ 2.4	1.3	
Minimum RRR	100	70	
Min. Ic at 4.2 K	Ic at 5 T	420 (A)	Ic at 7 T 510 (A)
	Ic at 6 T	330 (A)	Ic at 8 T 362 (A)
	Ic at 7 T	250 (A)	Ic at 9 T 230 (A)

Coil Excitation Results



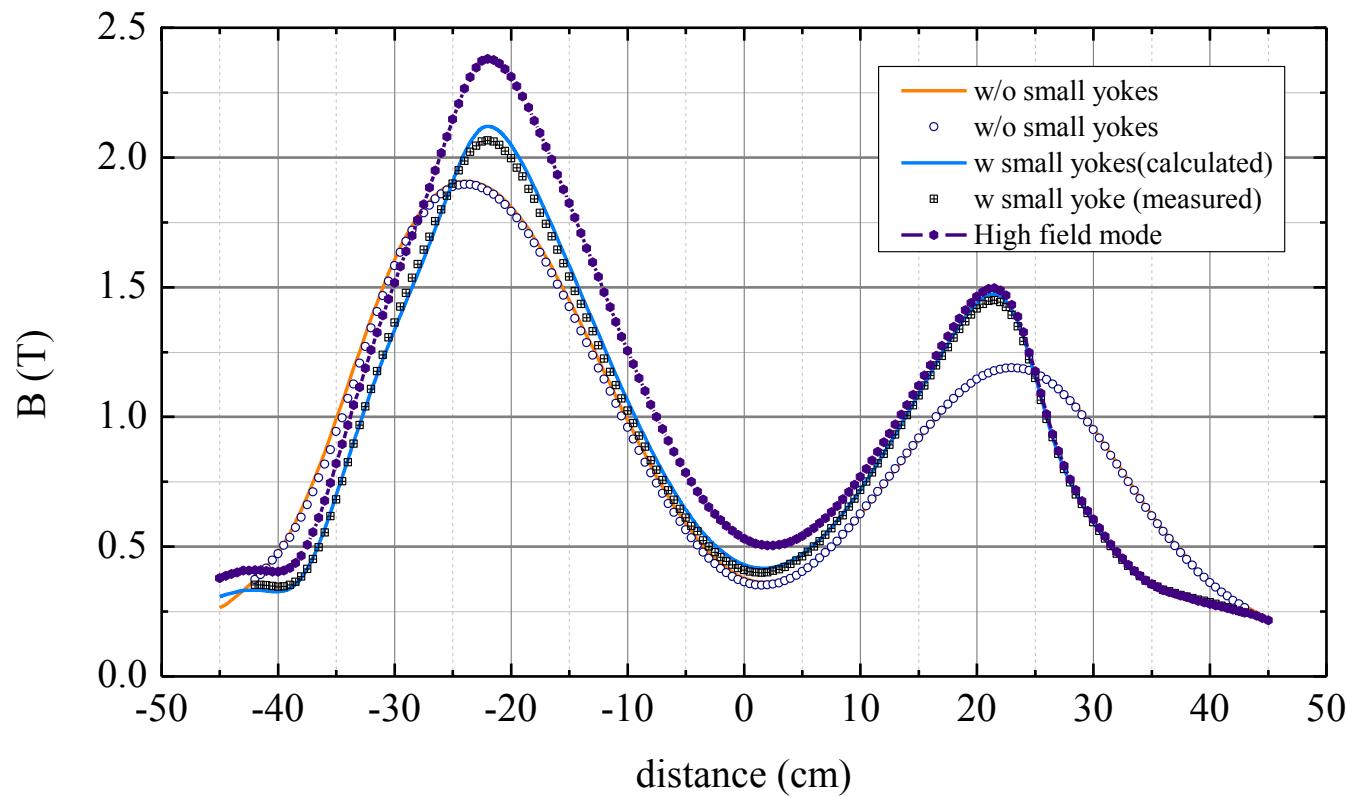
Test results of excitation/de-excitation speed (10 times higher)

Coil Excitation Results



Test results of excitation/de-excitation speed (10 times higher)

Magnetic field obtained



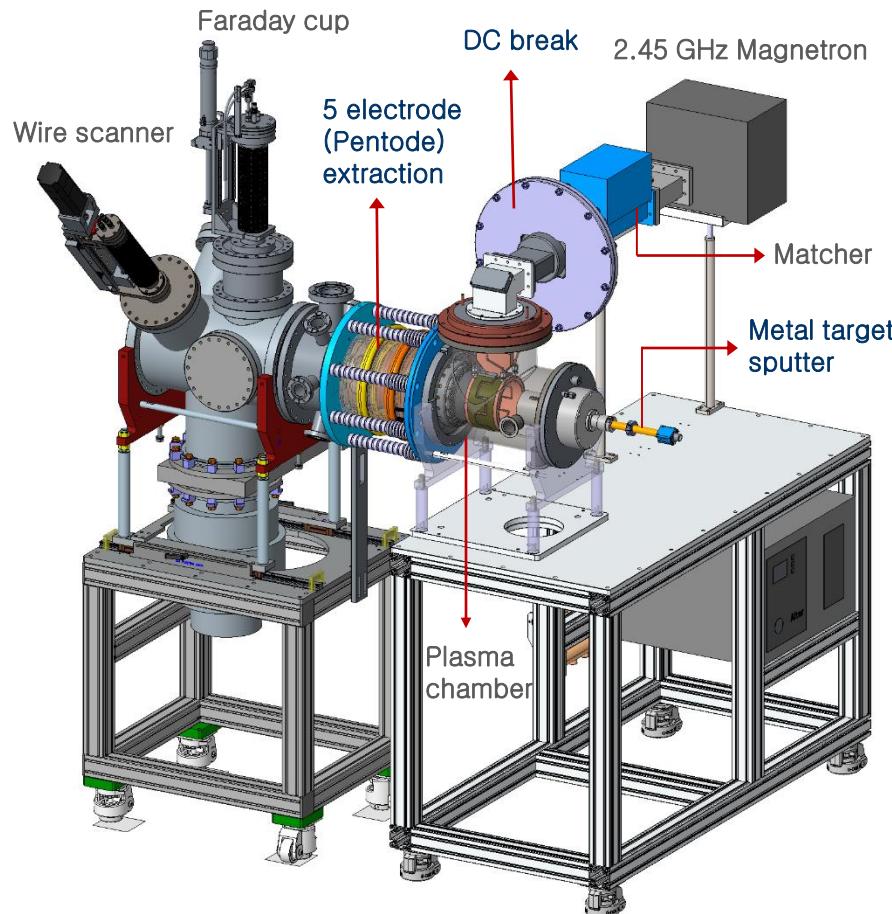
B-field profiles from the new fast ramping SC magnet II

MeLA ion source



MeLA ion source

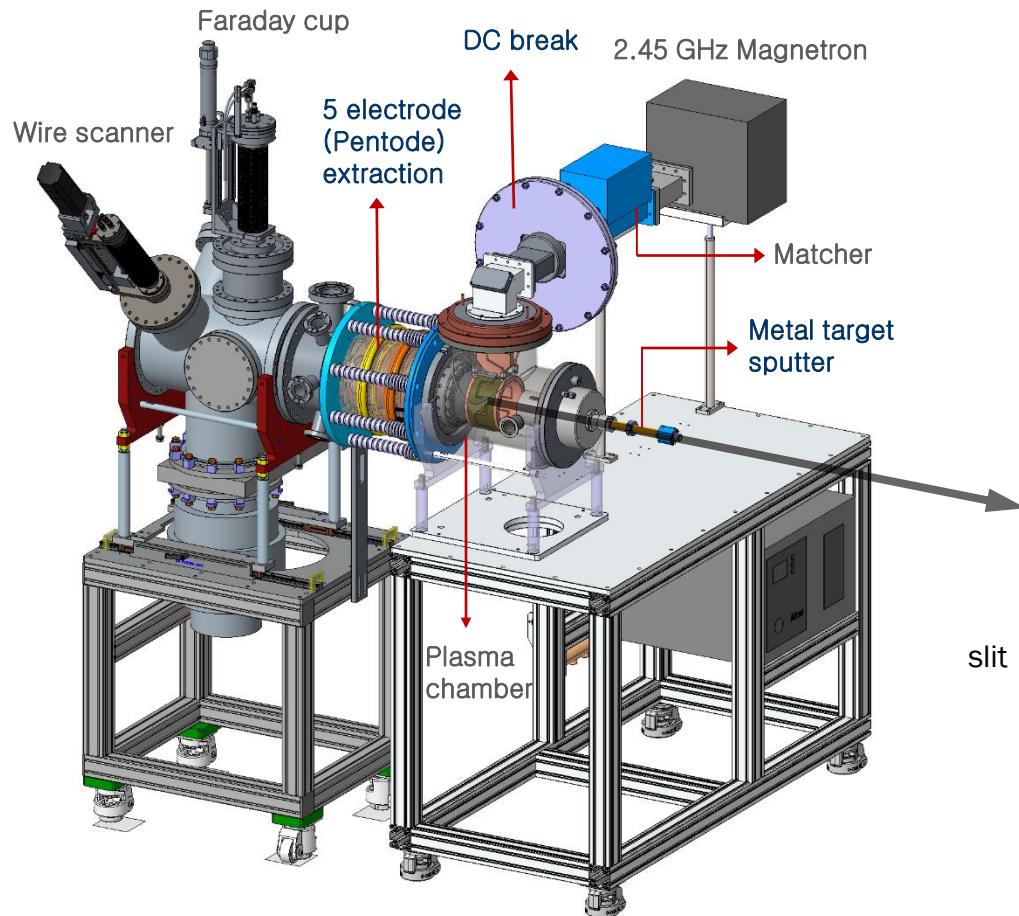
» MeLA (Magnet-embedded Lisitano Antenna): High Current Metal Ion Source



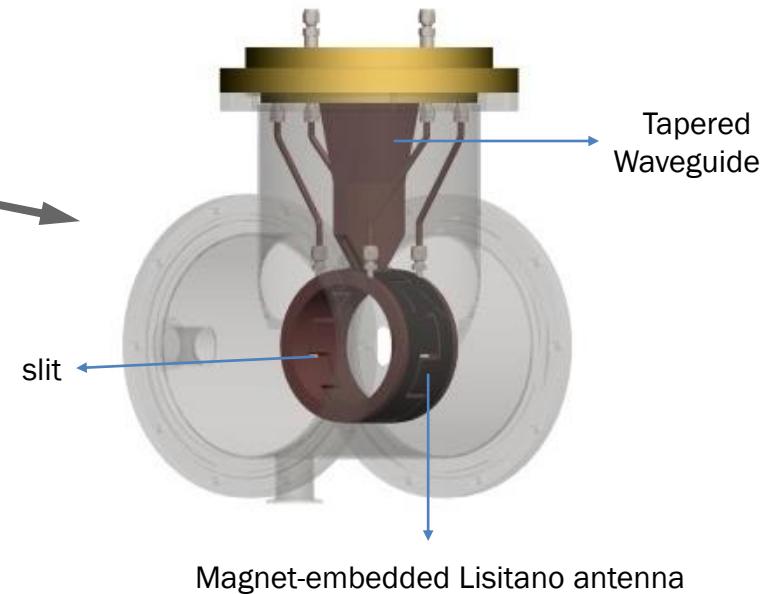
High current metal ion source

MeLA ion source

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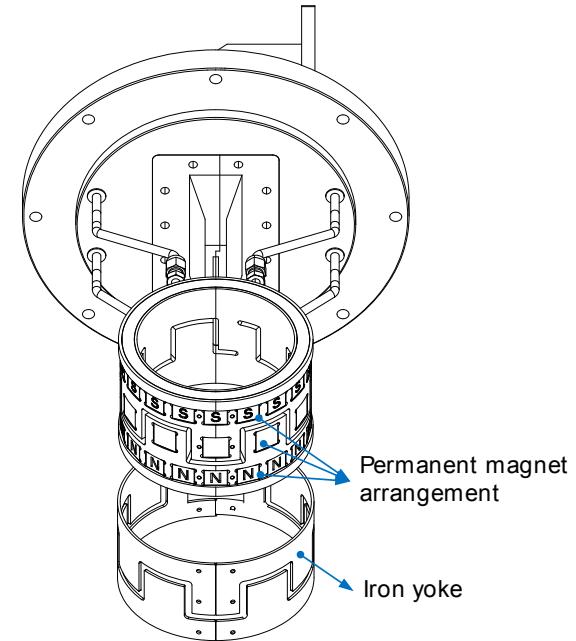
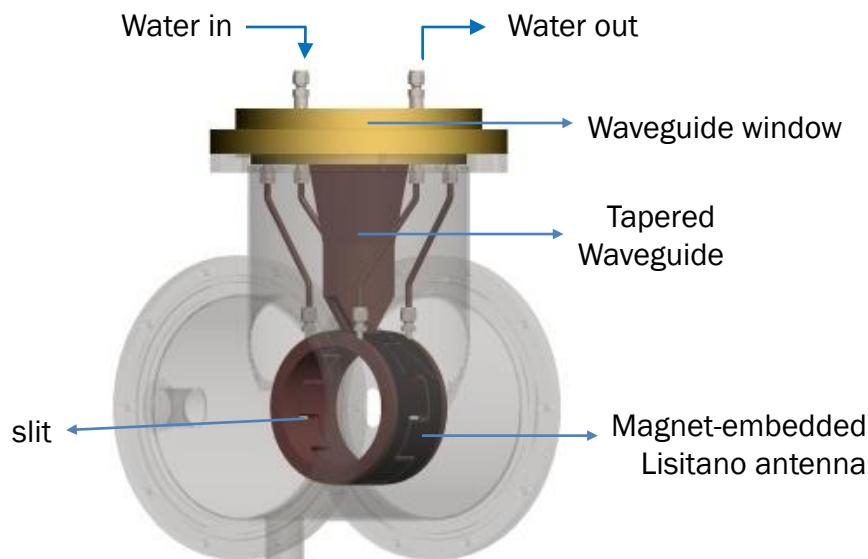
Magnet-embedded & WG directly-coupled
Lisitano Antenna



High current metal ion source

Antenna

Magnet-embedded & WG directly-coupled Lisitano Antenna



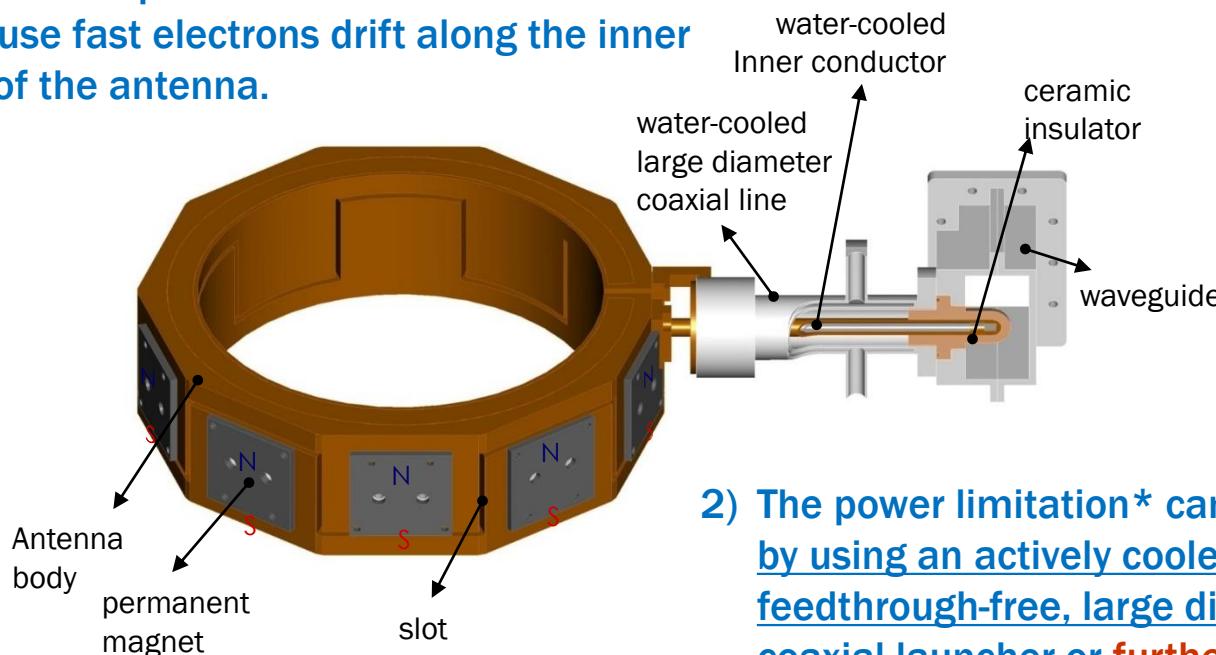
- Antenna diameter=Φ118 mm
- Number of slits= 11
- Number of magnets= 18 at Up/Down & 11 at Middle

Where is MeLA from? (1)

» MeLA was actually developed for a new plasma source by our team

1) By using the proper magnet arrangement,

Asymmetric profile can be reduced
because fast electrons drift along the inner
wall of the antenna.



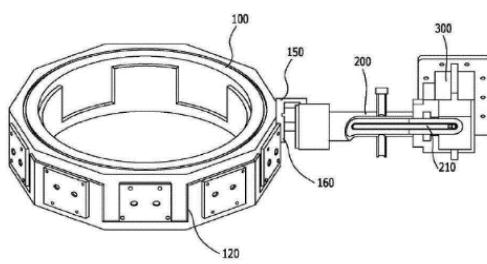
2) The power limitation* can be solved
by using an actively cooled,
feedthrough-free, large diameter
coaxial launcher or further waveguide
direct coupling.

* Conventional Lisitan antenna has a limitation
of power launching capability (< 1 kW),

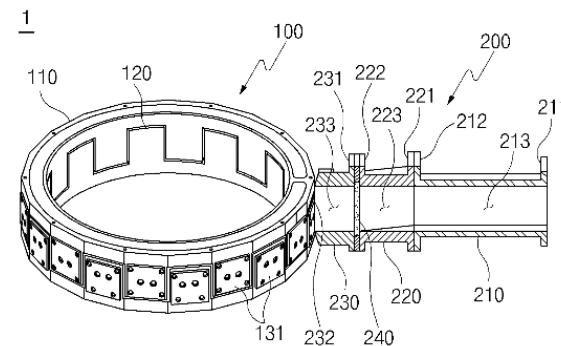
Where is MeLA from? (2)

» Two kind of Antenna excitations

(1) Coaxial excitation



(2) Waveguide excitation

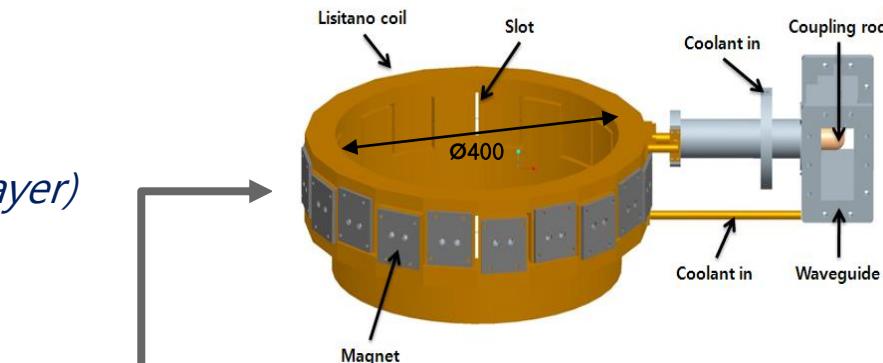
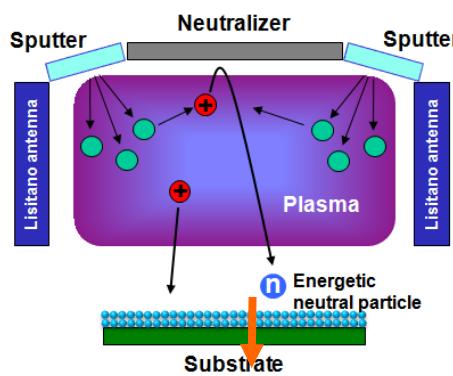


† H. J. You, Y. H. Jung, S. W. Jang, and B. J. Lee "Permanent magnet embedded Lisitano-coil driven antenna for large-area uniform plasma generation" Patent 10-2009-78248 31 August 2009.

Where is MeLA from? (3)

» MeLA has been used for a plasma processing

ex) Copper barrier/seed Layer)



PECVD



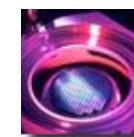
Metal(Cu, Ta, Al) Deposition



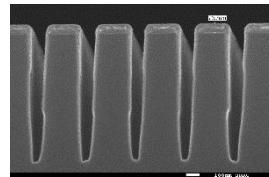
Ion Implantation



Ashing



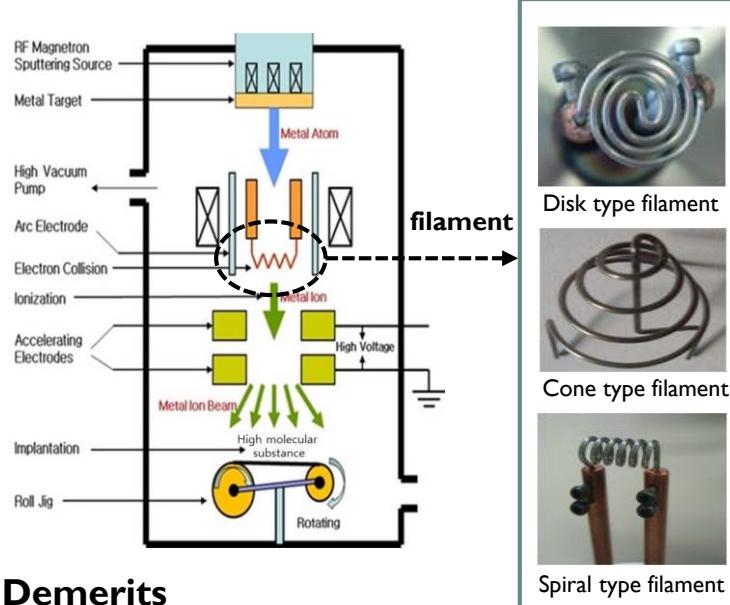
Etching



MeLA as a metal ion source

» MeLA's competitiveness as an metal ion source

Usual method: filament type(<10 μA)

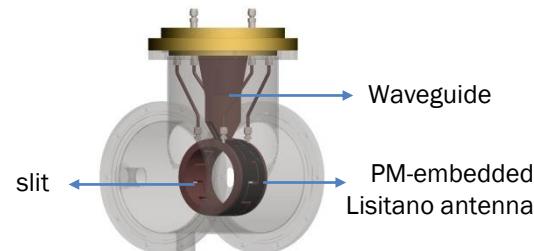


Demerits

- Short life (~100 hours)
- Difficulty to generate various metal ions
- Low plasma density (Beam intensity <10 μA)

New method: MeLA ion source(>1 mA)

Magnet-embedded & WG directly-coupled Lisisano Antenna

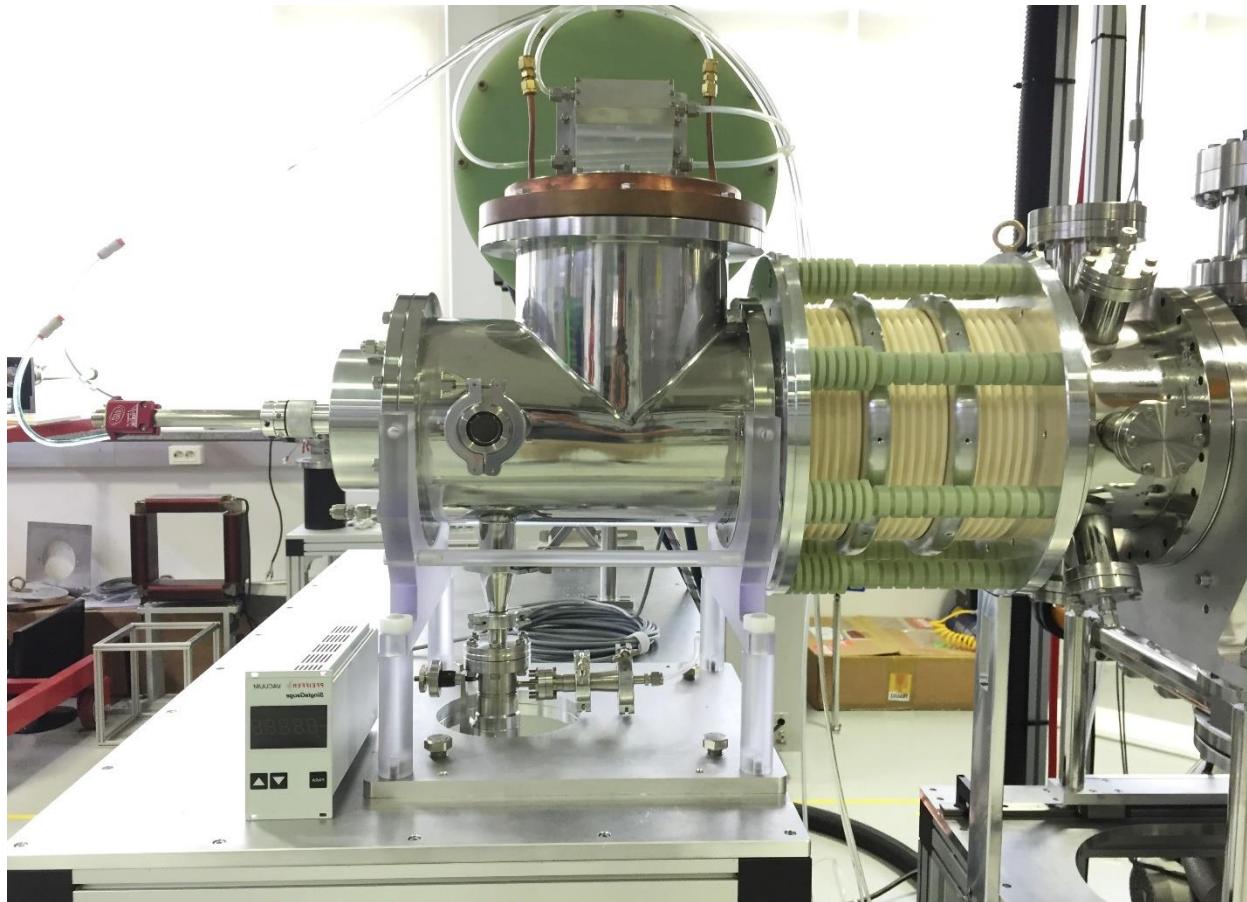


Advantages of MeLA ion source

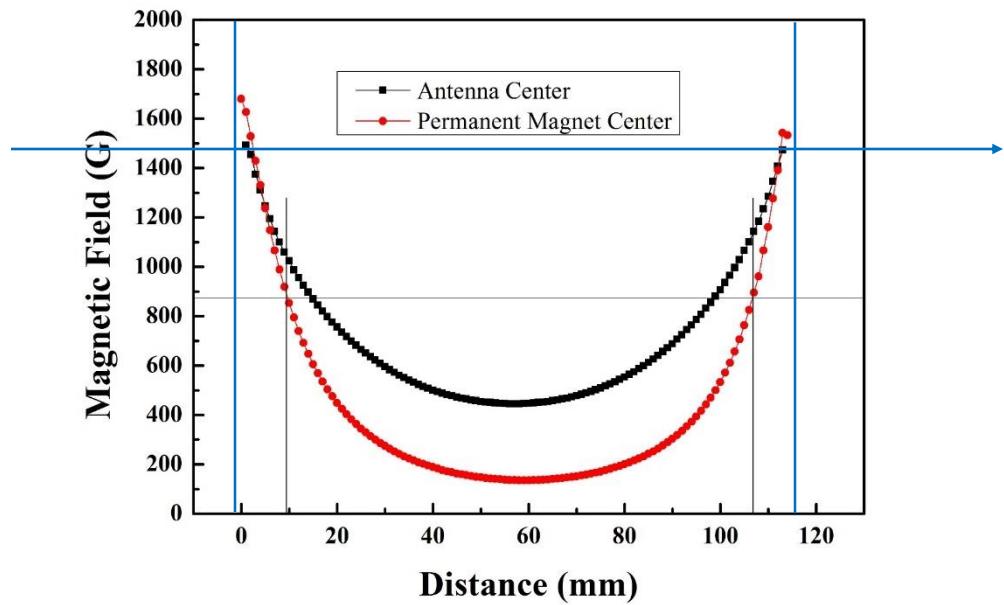
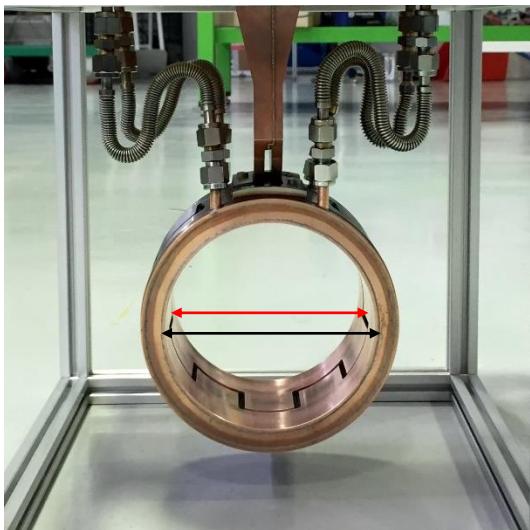
- Longer life & various metal ions
∴ metal antenna better for metal ion beam
- High density (10^{12} cm^{-3}) → 10 mA
- Low operating pressure < 1 mTorr
- Scalable (small to big size: 10 cm<1 M)

MeLA ion source at NFRI

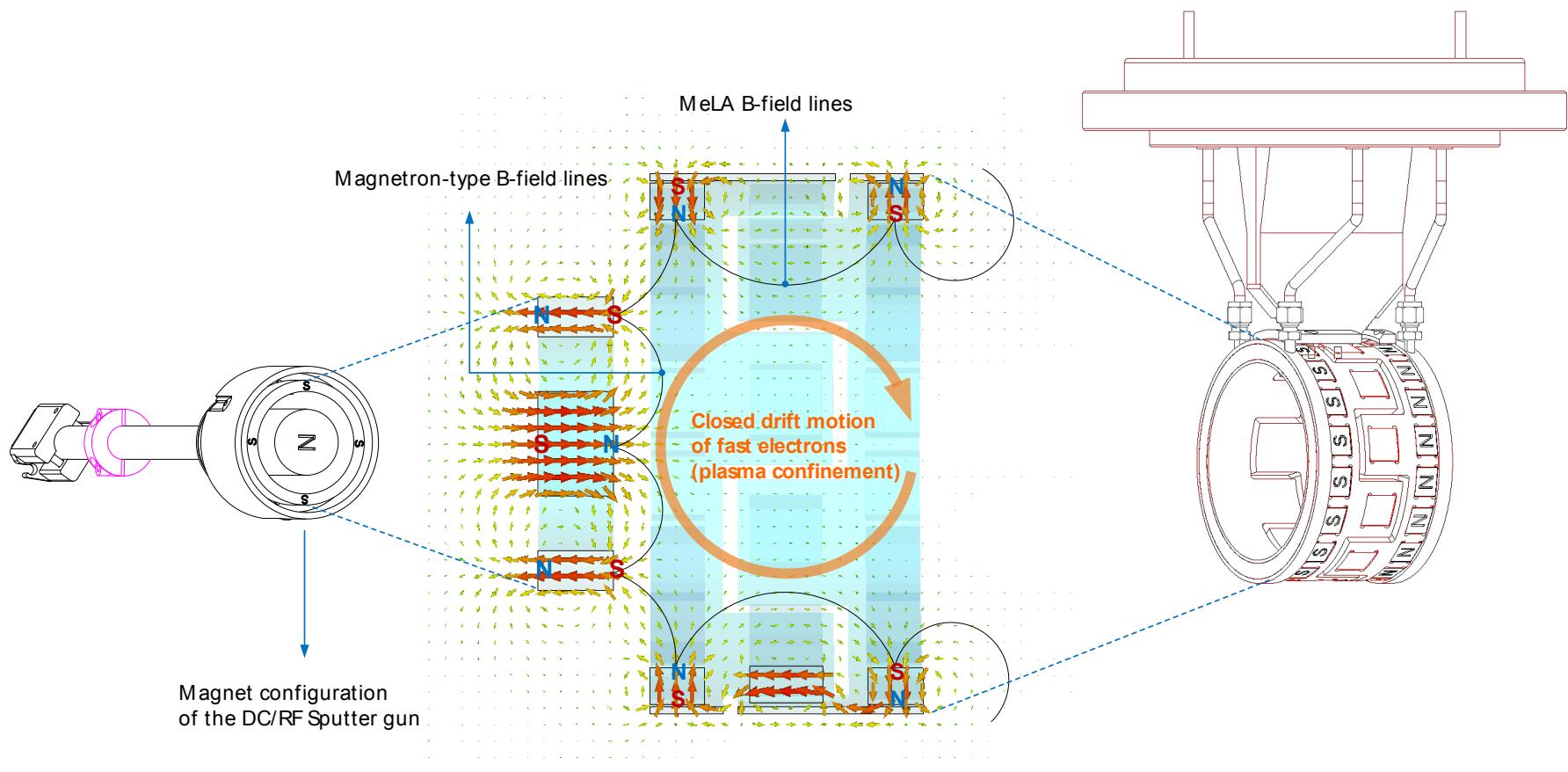
» MeLA for High Current Metal Ion Source



Magnetic field measurement



Combination of MeLA & Sputter B-field

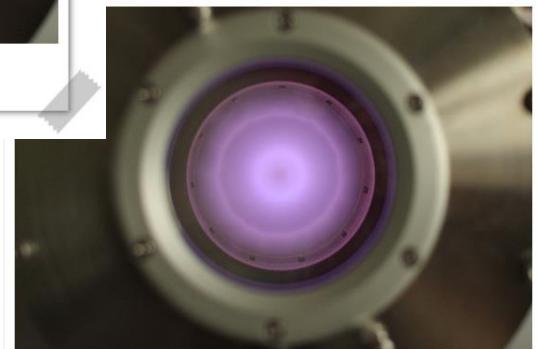
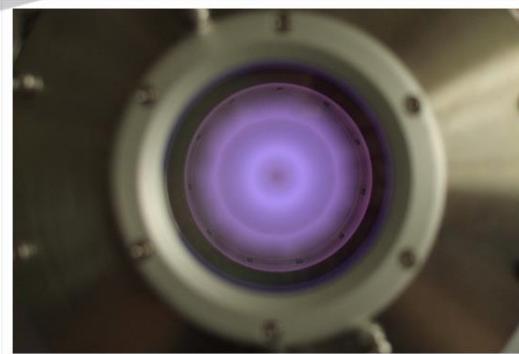
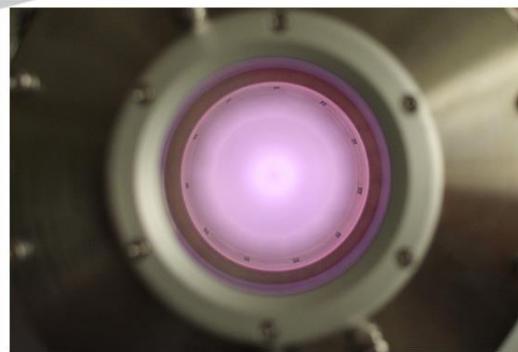
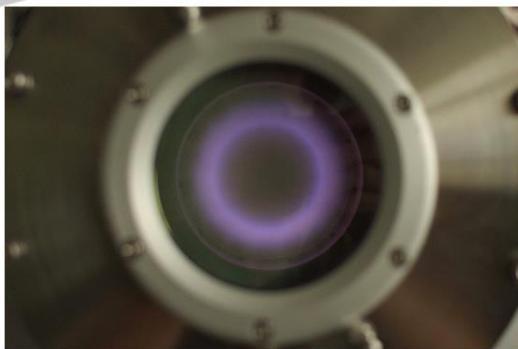


First Plasma We Get



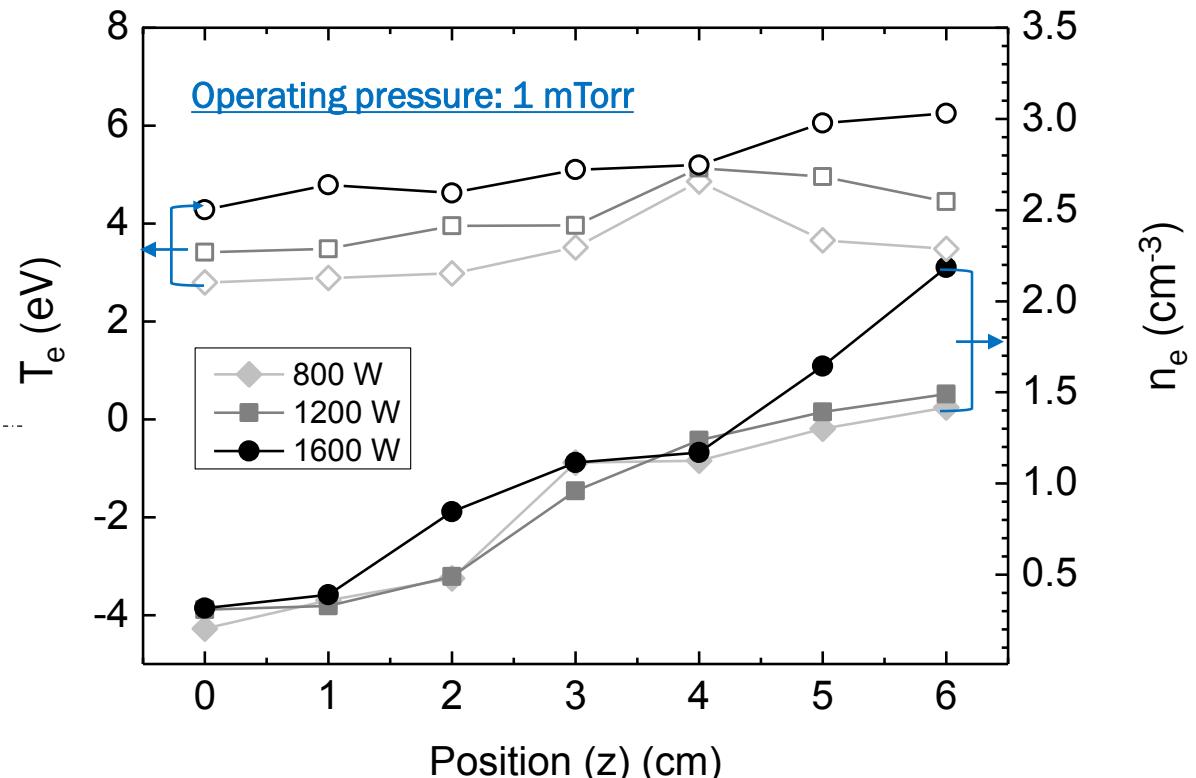
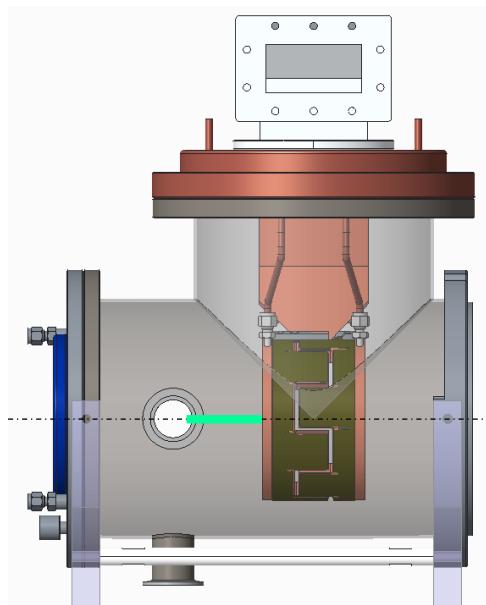
First Plasma Generation

» Generated plasma for argon gas



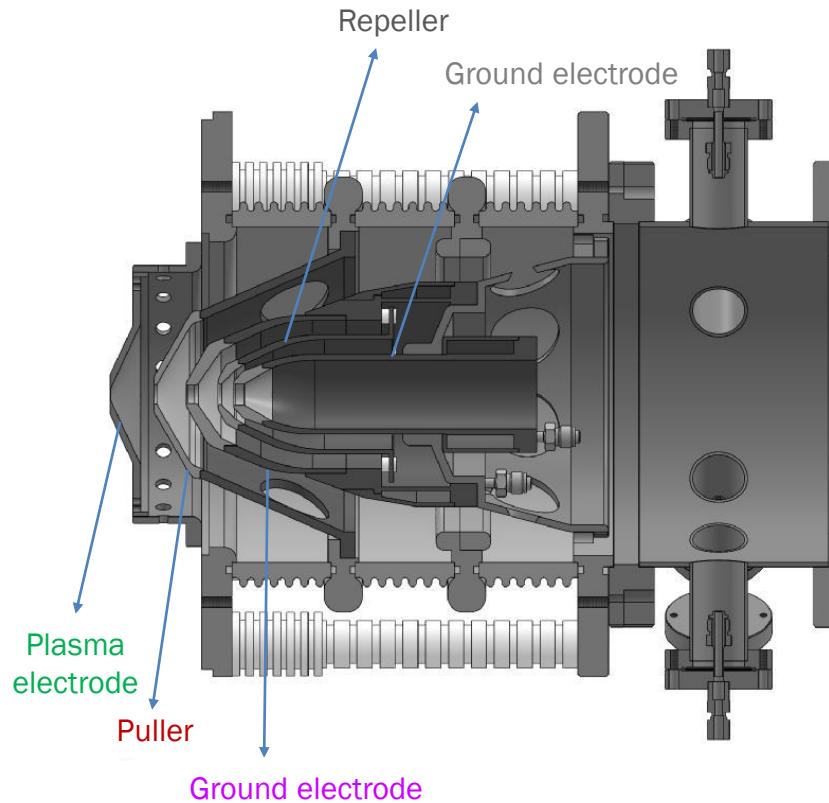
Measured plasma parameters

» Plasma densities & temperatures along the antenna axis for argon plasma



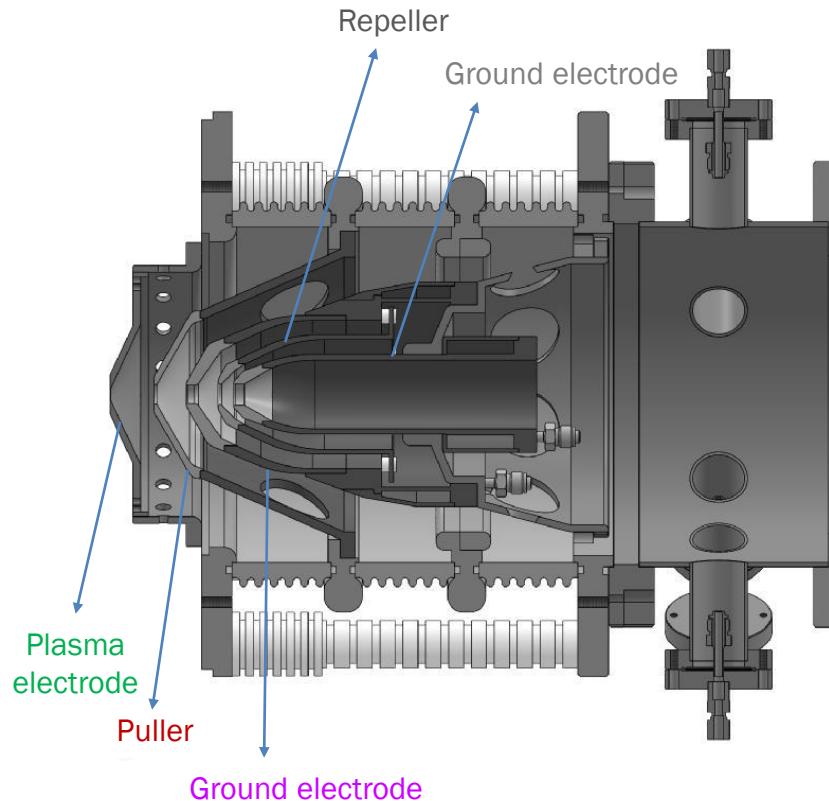
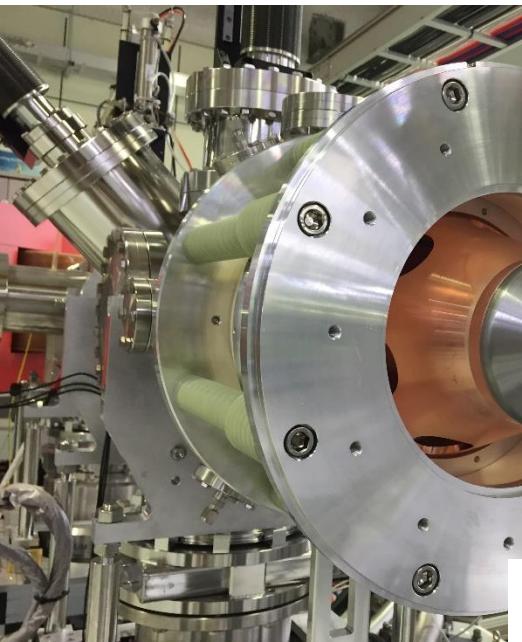
See the poster [WEPP17](#)
for more information & results

Pentode Extraction Structure



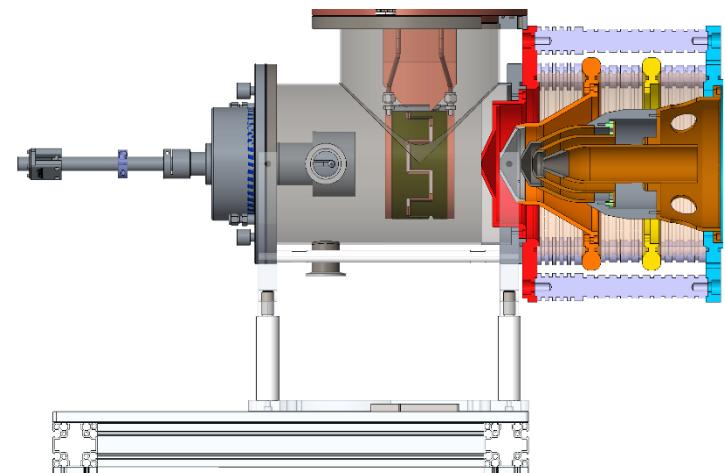
Pentode (5-electrode) extraction (*based on the extraction structure of Saclay/CEA source*)
Plasma electrode (100 kV), Puller (50 kV), Ground electrode 1 (0 kV), Repeller electrode (<-3 kV), Ground electrode 2 (0 kV)

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Summarized Features of MeLA



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» Easily-coupled ECR plasma → High current ion source

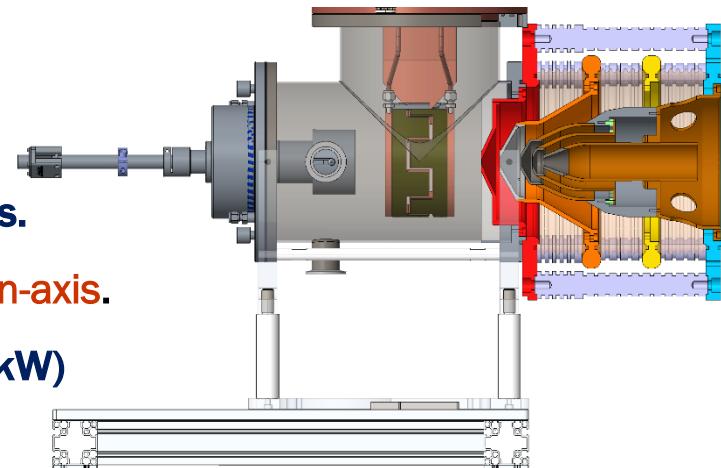
» Free scalability of ion source size (antenna)

» Side-excitation by a Metal antenna

→ Capability to generate diverse gas to metal ions.

→ Metal ion production by locating metal target on-axis.

» Waveguide directly-coupled (power capability >2 kW)



» Permanent magnet-embedded antenna

→ No electric power & water cooling for magnet; so, No high-voltage platform

» 5-electrode (pentode) extraction geometry (100 kV) for high current space charge-compensated beam & low beam emittances (High brightness)

» Low operating pressure < 1 mTorr (small gas/metal usage)

Commissioning schedule



Commissioning schedule

» More plasma study: **Sep./2016**

- 1) Plasma characterization by diagnostics
(optimization of sputter position)
- 2) plasma density at extraction region
plasma electrode position)

» Extraction system commissioning: **Nov./2016**

- 1) Optimum extraction field with plasma condition
- 2) All power supplies are ready to be used.
- 3) High-power FC, BPM are ready, &
Emittance scanner is in fabrication.

» **First beam results are expected in Dec./2016**



고맙습니다
(Thank you so much)